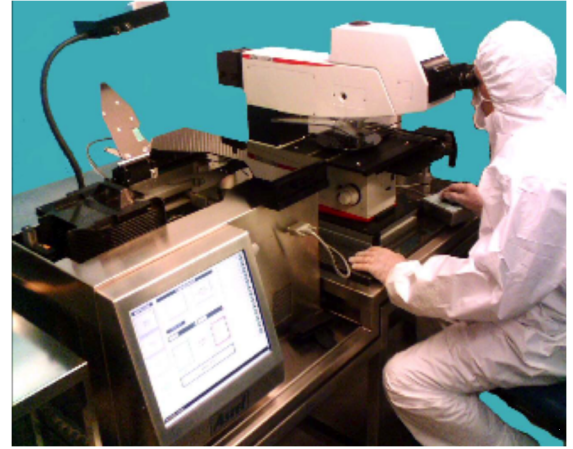


Technology for a friendly use

The new Proteus Inspection Loader is a tool dedicated to wafer micro and macro inspection tasks. This equipment has been designed to fulfill the needs of short cycle times as well as the increasing difficulties due to thin wafers handling.

Such needs required a careful design, based on the state of the art technological solutions for both mechanics and control system.

The Proteus Loader, in its fully equipped version, features micro and macro inspection capabilities, including a backside inspection with the full view of wafer bottom.



Specifications	
Wafer size	150 - 200 mm - single or multi size
Wafer thickness	170 – 1200 µm
Clean room compatibility	Class 10 clean room compatible
Control	Computer control with touch screen operator interface
Type of inspection	Front macro, back macro, micro inspection
Inspection mode	Sequential, sampling or statistical access
Centering	Position controlled edge aligner
Cassette mapping	Laser sensor with thin wafer detection capability
Compatible microscopes	Astel MX-R - Other semiconductor inspection microscopes
Footprint	W 800 x D 700 x H 650 (including Back unit in up position)
Macro illuminators	Pure green or white LED units for front and back inspection
Facilities	AC 220 - 240 V - 3,5 A 50 /60 Hz Vacuum - 60 to -90 KPa - 10 l/min Compressed air or nitrogen - 6 bar - 60 nl/min

(Specifications are subject to change without any obligation on the part of manufacturer)

